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- PATENT

Docket No.: 2336-086 114 07 700

TATHELINTED STATES PATENT AND TRADEMARK OFFICE

(74	LK-142				
In re Application of					
Jeong-Goo YOON et al.			: : Confirmation No. 9603		
U.S. Patent Application No. 10/006,143			: Group Art Unit: 2823		
Filed: December 10, 2001			Examiner: G. Fourson III		
For: PROCESS FOR LAPPING WAFER AND METHOD FOR PROCESSING BACKSIDE OF WAFER USING THE SAME					
Dear Sir:					
Transmitted herewith is an	Amendment in	n the above identified	l application.		
<ul> <li>No additional fee is r</li> <li>Small entity status of</li> <li>Also attached: Exhib</li> <li>The fee has been calculate</li> </ul>	this application its A-C		d.		
	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	14	20	0	x \$ 18 =	\$ 0.00
Independent Claims	3	3	0	x \$ 86 =	\$ 0.00
			wly presented, add \$2	290.00	n/a
		Fee for extension of	time		n/a
			T	OTAL FEE DUE	\$ 0.00
A credit card authoris	zation form in t	the amount of	is atta	ched	
The Commissioner is or credit any overpay for presentation of ex	ment, to Depos	sit Account No. <u>07-1</u>	337, including any	filing fees under 3	

Respectfully submitted,

LOWE MAUPTMAN GILMAN & BERNER, LLP

Benjamin J. Hauptman Registration No.: 29,310

USPTO Customer No. 22429 1700 Diagonal Road, Suite 300 Alexandria, Virginia 22314 (703) 684-1111 BJH/klb (703) 518-5499 Facsimile Date: January 7, 2004 **Docket No.: 2336-086** PATENT

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Jeong-Goo YOON et al.

Confirmation No. 9603

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For:

PROCESS FOR LAPPING WAFER AND METHOD FOR PROCESSING BACKSIDE

OF WAFER USING THE SAME

## **AMENDMENT**

Commissioner for Patents P.O. Box 1450 Alexandria VA 22313-1450

Sir:

The following amendments and remarks are submitted in response to the Official Action dated *October 7, 2003*.